

1731

## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Akira IKUSHIMA, Kazuya SAITO, Takashi MIURA  
and Shogo NASUDA  
Serial no. : 09/848,246  
Filed : May 3, 2001  
For : METHOD OF MANUFACTURING AN OPTICAL  
FIBER  
Group Art Unit : 1731  
Examiner : John M. Hoffmann  
Docket : ADACHI P163USP2

The Commissioner for Patents  
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**ADDENDUM TO INFORMATION DISCLOSURE STATEMENT**

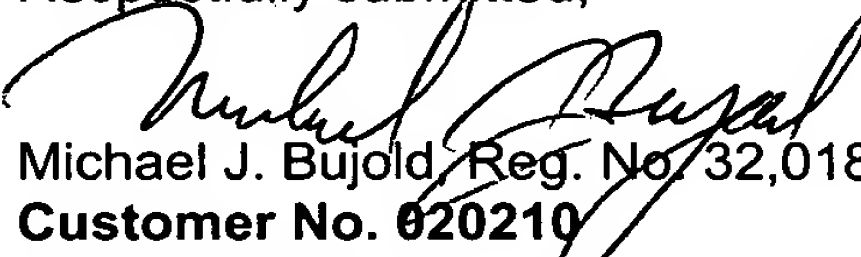
Dear Sir:

Further to the Information Disclosure Statement mailed under a May 3, 2001 Express Mailing date, enclosed is a copy of the three (3) references which was not previously available and indicated as "(to follow)".

This submission is believed to complete the filing of the above referenced Information Disclosure Statement. If any further action on the part of the Applicant is necessary to make this art properly of record, the Examiner is respectfully requested to contact the undersigned.

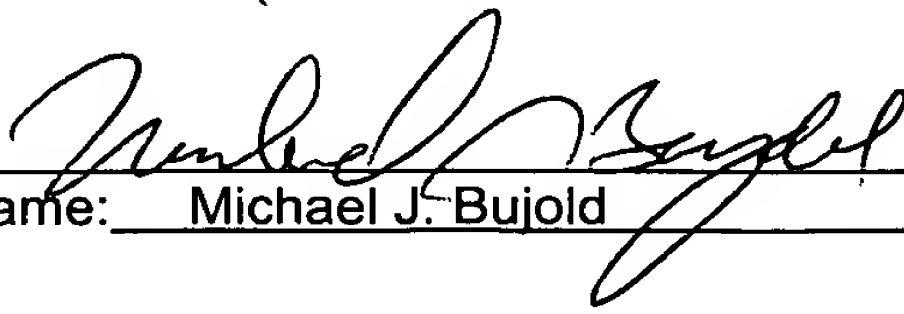
In the event that there are any fee deficiencies or additional fees are payable, please charge the same or credit any overpayment to our Deposit Account (Account No. 04-0213).

Respectfully submitted,

  
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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service, with sufficient postage, as First Class Mail in an envelope addressed to: Director of the United States Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450.  
December 5, 2003.

By:   
Print Name: Michael J. Bujold



PATENT AND TRADEMARK OFFICE  
INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT  
(Use several sheets if necessary)

Atty Docket: A10001 P163USP2

Examiner: John J. Hoffmann

Group: 1731

Applicant: Akira IKUSHIMA, Kazuya SAITO, Takashi MIURA and Shogo NASUDA

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Sub-Class	Filing Date, if Appropriate
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	4,157,253	Jun. 1979	Hemquist		
	4,182,664	Jan. 1980	Maklad		
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	6,058,739	May 2000	Morton		
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	2808457	Aug. 1974	Germany			
	4-342427	Nov. 1992	Japan			(To follow)
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	6-199539	Jun. 7, 1994	Japan			
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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

"Thermal Annealing of Defects Induced by Arf Excimer Laser Irradiation in a SiO<sub>2</sub>"; Japanese Society of Applied Physics, Catalog No. AP 90110-02 (English Translation) (To follow)

ROTHSCHILD, Mordechai, Daniel J. EHRLICH and David C. SHAVER, "Eximer Laser Induced Damage in Fused Silica", *Microelectronic Engineering* 11, 1990, pp. 167-172.

"Temperature Dependence of the E' Center Creation in Silica Glasses", *Physica Status Solidi (b)*, vol. 147, No. 1, 1988, pp.k1-k4.

Examiner

Date Considered